

**Amendments to the Specification**

Rewrite the first partial paragraph on page 13 as follows:

hydrazine. For example, a cantilever can be made of this etch-stop material system, then released from its substrate and surrounding material, i.e., “micromachined”, by exposure to one of these etchants. These solutions generally etch any silicon containing less than  $7 \times 10^{19} \text{ cm}^{-3}$  of boron or undoped  $\text{Si}_{1-x}\text{Ge}_x$  alloys with  $x$  less than approximately 0.18.